

Crystalline-Silicon Solar Cells for the 21st Century

Y.S. Tsuo, T.H. Wang, and T.F. Ciszek

*Presented at the Electrochemical Society
Annual Meeting
Seattle, Washington
May 3, 1999*



NREL

National Renewable Energy Laboratory

1617 Cole Boulevard
Golden, Colorado 80401-3393

NREL is a U.S. Department of Energy Laboratory
Operated by Midwest Research Institute • Battelle • Bechtel

Contract No. DE-AC36-98-GO10337

NOTICE

This report was prepared as an account of work sponsored by an agency of the United States government. Neither the United States government nor any agency thereof, nor any of their employees, makes any warranty, express or implied, or assumes any legal liability or responsibility for the accuracy, completeness, or usefulness of any information, apparatus, product, or process disclosed, or represents that its use would not infringe privately owned rights. Reference herein to any specific commercial product, process, or service by trade name, trademark, manufacturer, or otherwise does not necessarily constitute or imply its endorsement, recommendation, or favoring by the United States government or any agency thereof. The views and opinions of authors expressed herein do not necessarily state or reflect those of the United States government or any agency thereof.

Available to DOE and DOE contractors from:
Office of Scientific and Technical Information (OSTI)
P.O. Box 62
Oak Ridge, TN 37831
Prices available by calling 423-576-8401

Available to the public from:
National Technical Information Service (NTIS)
U.S. Department of Commerce
5285 Port Royal Road
Springfield, VA 22161
703-605-6000 or 800-553-6847
or
DOE Information Bridge
<http://www.doe.gov/bridge/home.html>



CRYSTALLINE-SILICON SOLAR CELLS FOR THE 21ST CENTURY

Y.S. Tsuo, T.H. Wang, and T.F. Cizek
 National Renewable Energy Laboratory
 MS-3213, 1617 Cole Blvd., Golden, CO 80401 USA

ABSTRACT

The worldwide market share for crystalline-silicon solar cells has increased steadily in the last 10 years. In 1998, about 87% of the photovoltaic modules shipped worldwide are based on crystalline silicon. This dominance will likely continue into at least the first few years of the 21st century. The long-term growth of crystalline-silicon solar cells will depend on the development of low-cost polysilicon feedstock, silicon films, and advanced cell and module manufacturing processes.

INTRODUCTION

The worldwide photovoltaic (PV) module shipments for terrestrial applications reached 152 MW/year in 1998. Crystalline-silicon (c-Si) solar cells currently account for about 87% of the worldwide PV module shipment (Fig. 1 and Table I).

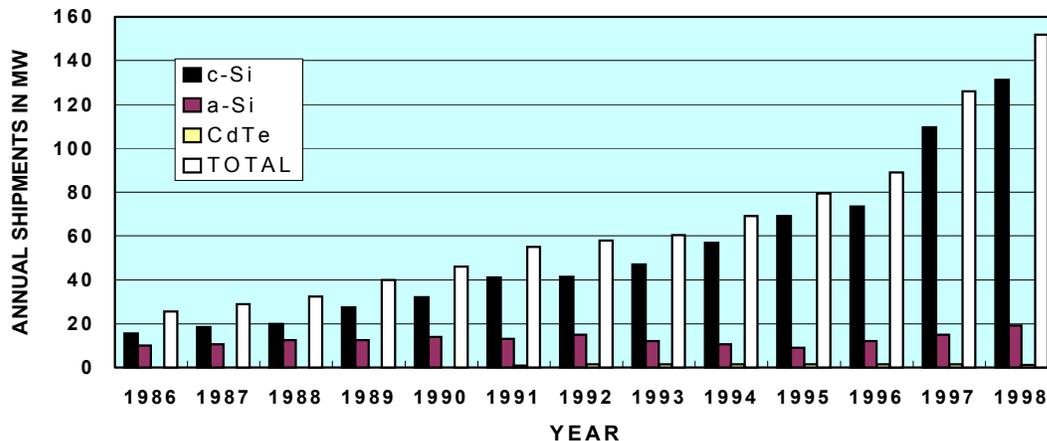


Figure 1. Worldwide PV shipments (in MW) by material technology.
 (Main source of data: *PV News*, Paul D. Maycock, editor)

Table I. Overall market share for c-Si PV modules from 1990 to 1998
 (including single-crystal, polycrystalline, ribbon, and concentrator Si)

	1990	1991	1992	1993	1994	1995	1996	1997	1998
World (%)	67.7	73.8	72.7	77.3	81.3	82.1	82.9	83.3	86.5
U.S. (%)	90	95	93	96	96	96	96	94	93

There are many reasons for the dominance of c-Si in PV: stable performance, low module manufacturing cost (presently less than \$2.5/W_{peak}), and mostly non-toxic materials used in the final product. There are four types of c-Si solar cells: single-crystal, polycrystalline, ribbon, and silicon film deposited on low-cost substrates. In 1998, market shares of the worldwide PV cell and module shipment for the four types of crystalline-silicon solar cells were 39.4% for single-crystal, 43.7% for polycrystalline, 2.6% for ribbon, and 0.7% for silicon film (1). This is the first time ever that polycrystalline silicon has overtaken single-crystal silicon as the PV market leader.

We believe that to ensure the continued growth of the c-Si PV industry in the next century, three research and development areas (2,3) need to be extensively investigated in the near future: (1) innovative approaches for producing low-cost polysilicon feedstock, (2) low-temperature, high-throughput, thin-layer silicon deposition methods, and (3) environmentally benign cell and module manufacturing processes. In this paper, we will identify the main issues that need to be addressed for each of these activities.

LOW-COST POLYSILICON FEEDSTOCK

For crystal-growth feedstock, the c-Si PV industry has been relying on waste material from the semiconductor Si industry and on *secondary polysilicon*, the excess or rejected material from electronic-grade polysilicon production. This amounts to about 10% of the polysilicon material used by the semiconductor Si industry. If the PV industry continues to grow at the present rate, which in recent years has been higher than the growth rate of the integrated-circuit industry, new sources of polysilicon will be needed (4,5). New approaches need to be investigated for producing solar-grade polysilicon at costs of less than US\$10/kg. The purity requirements for solar-grade polysilicon, according to the Solar-Grade Silicon Stakeholders Group, are the following: it is preferred that polysilicon have either B or P doping, with no compensation; resistivity at 25°C should be greater than 1 ohm-cm; oxygen and carbon should not exceed the saturation limits in the melt; and the total non-dopant impurity concentration should be less than 1 ppma (6).

More than 98% of semiconductor-grade polysilicon is produced by the trichlorosilane (SiHCl₃) distillation and reduction method (7). This method of polysilicon production is very energy intensive, and it produces large amounts of wastes, including a mix of environmentally damaging chlorinated compounds (8). About 80% of the initial metallurgical-grade silicon (MG-Si) material is wasted during the process. In addition, the semiconductor-grade polysilicon material produced by this method far exceeds the purity requirement of the PV industry, and the cost (over US\$50/kg, with most of it attributable to the SiHCl₃ processes) is several times higher than what the PV industry can afford. Recently, several programs have been initiated to investigate less energy-intensive and chlorine-free methods of producing solar-grade polysilicon. Examples include a method that uses MG-Si and absolute alcohol as the starting materials (2), a method of producing solar-grade polysilicon by directly purifying MG-Si pellets using porous silicon etching and

subsequent annealing (9), and a method of using an electron-beam furnace and a plasma furnace to remove impurities from MG-Si (10).

SILICON FILMS

Thin-Layer Polycrystalline Silicon

Thin-layer c-Si solar cells have great potential for low cost, high efficiency, low material consumption, long-term stability, and environmental friendliness. The challenge in developing this technology is in fabricating an active silicon layer of sufficient electronic quality, with a thickness of 10 microns or more, at a deposition rate of over 1 micron/min, and on a low-cost substrate such as glass. The principal requirement on electronic quality is a long minority-carrier diffusion length that is at least comparable to the layer thickness.

Liquid-phase epitaxy (LPE) growth methods have been extensively studied to produce thin silicon layers on low-cost MG-Si silicon substrates (11). One of the more successful methods, which uses Cu-Al solvents for LPE growth of silicon, provides higher growth rates (~1 micron/min) and better nucleation than commonly used indium solvent and yet suppresses Cu and Al incorporation in the layer better than Cu or Al alone (12). The crystal perfection achieved by LPE is inherently better than gas-phase growth techniques because of the near-equilibrium growth process. However, this also limits the substrate choice to silicon because the free-energy driving force in LPE is usually not enough for nucleation on foreign substrates without incurring simultaneous nucleation in the liquid.

Gas-phase growth techniques can deposit large-grain polycrystalline thin-layer silicon on a foreign substrate at a high rate with minimum contamination. The technique needs to provide enough driving force for heterogeneous nucleation and reduced number of nucleation sites. Alternately, a seeding silicon layer on a foreign substrate may be used. However, conventional chemical-vapor deposition (CVD) methods have had only limited success in depositing thin-layer silicon for PV applications. For example, thermal CVD requires too high a substrate temperature (13), and plasma-enhanced CVD (PECVD) has too slow a deposition rate for low-cost thin-layer polycrystalline silicon (14). Post-deposition solid-phase crystallization can be a way of avoiding the aforementioned limitations of deposition methods (15). However, the disadvantages of solid-phase crystallization include low throughputs and the tendency to induce stress in the films. Alternatively, advanced light-trapping techniques can reduce the thickness requirement for thin-film silicon solar cells and make it feasible to use low-deposition-rate methods. For example, a PECVD-deposited, 2-micron-thick polycrystalline silicon solar cell with light trapping was shown to have a conversion efficiency of more than 10% (16).

Atmospheric pressure and rapid thermal CVD (AP-RT-CVD) seems to be a promising method to achieve fast deposition of polycrystalline silicon layers on foreign substrates (17). However, to achieve adequate grain sizes, the depositions had to be done at elevated substrate temperatures. This speeds up impurity contamination and limits substrate selections. The challenge is to find a growth method that has a driving force between that of the LPE and the AP-RT-CVD techniques to facilitate

sparse nucleation on foreign substrates for fast deposition of large-grain silicon layers at relatively low temperatures.

Microcrystalline Silicon

Microcrystalline (or nanocrystalline) silicon films produced by plasma-enhanced chemical-vapor deposition (PECVD) through a glow discharge containing silane diluted in argon, helium, and/or hydrogen have optical and electrical properties different from hydrogenated amorphous silicon and conventional polycrystalline silicon (18). These microcrystalline silicon films are often a mixture of hydrogenated amorphous silicon and polycrystalline silicon grains, with grain size from a few nanometers to a few hundred nanometers. These films can exhibit optical properties characteristic of a direct bandgap material (19). They have higher electrical conductivity and mobility than hydrogenated amorphous silicon. Microcrystalline silicon films are widely used as contact layers and tunnel junctions in amorphous silicon and multiple-junction solar cells. A solar cell using microcrystalline silicon as the active layer was reported with a high initial efficiency of 13.1% (20, 21). Plasma deposition methods and low deposition temperatures make it easy for depositing microcrystalline silicon solar cells on low-cost substrates over large areas. However, low deposition rates and light-induced degradation are concerns for microcrystalline solar cells.

Porous Silicon

It was discovered in 1990 that porous silicon formed on crystalline-silicon wafers using electrochemical etching exhibits photoluminescent and electroluminescent properties similar to those properties of a semiconductor with a direct energy gap (22). Porous silicon layers can be easily produced on single- or multicrystalline silicon surfaces by electrochemical or stain etching at very low cost. Several possible methods of using porous silicon to improve the performance of crystalline silicon solar cells have been proposed since then. It was shown that a porous silicon-etched silicon surface has excellent anti-reflection properties (23). Porous silicon may also serve as a wide bandgap absorber in a multiple-junction cell structure, with crystalline silicon as the substrate or as gettering centers to reduce the impurity levels in a silicon substrate (24). A porous-silicon back-surface reflector has been demonstrated for thin-film silicon solar cells (25). Attempts were even made to use two porous silicon layers with two different bandgaps in a three-bandgap solar cell on a silicon wafer (26). Although porous silicon has not yet been used in any commercial silicon solar cell yet, it remains a potential resource for improving the crystalline-silicon solar cell technology.

ADVANCED CELL AND MODULE MANUFACTURING PROCESSES

Environmentally Benign Manufacturing Processes

The manufacturing of c-Si solar modules -- from polysilicon production, to crystal growth, ingot slicing, wafer cleaning, cell processing, and encapsulation -- requires many steps that are energy intensive and uses large amounts of water and toxic chemicals. As the c-Si PV industry continues to expand, the environmental impact of its manufacturing processes and products will receive increasing attention, because one of the primary benefits of renewable-energy generation is its low environmental

impact. Examples of new and more environmentally benign approaches for manufacturing silicon cells and modules include (2):

- Automated processes for handling thin (< 200-micron-thick) silicon wafers (27),
- Defect passivation methods to improve cell conversion efficiency (28),
- Water-soluble or water-based slurries for multiple-wire saws and slurry recycling,
- Reduction, recovery, recycle, reuse, and substitution for water and chemical usage for wafer cleaning and etching,
- Reducing or eliminating the use of perfluorinated compounds for cell processing,
- No-clean flux, and
- Lead-free solder.

Environmentally benign manufacturing approaches often have the added benefit of cost reduction by reducing energy use and/or the purchase volume of new chemicals and by cutting the amount of spent chemicals that must be discarded. A good example of a new, more environmentally benign approach that also improves module performance is the Sn(96.5)/Ag(3.5) lead-free solder. A recent report (29) shows that this solder has better thermal performance characteristics over the industry standard Sn(60)/Pb(40) solder in commercially available photovoltaic modules.

Rapid Thermal Processing

Rapid thermal processing (RTP, 30) has some important advantages over traditional furnace processing, including shorter process times, lower thermal budgets, lower chamber wall temperatures, and better control over ambient conditions due to reduced reactor volume (31). Possible applications of RTP in crystalline-silicon solar cell processing include junction formation (32), selective doping (33), thermal oxidation, and drying and firing of screen-printed metal pastes. Concentrated light may also be used for solid-phase crystallization of thin-film silicon (34). However, the high cost and low throughput of single-wafer RTP systems limit the use of RTP's application in PV solar cell manufacturing. Multiple-wafer RTP systems have become commercially available recently. However, the cost of such systems is still too high compared to traditional furnaces. In addition to the thermal effects, photons with energy near or above the bandgap energy may also have beneficial effects (35, 36). However, more studies are needed to more clearly demonstrate these benefits.

CONCLUSIONS AND DISCUSSION

With increasing automation and economy of scale, the present generation of crystalline-silicon solar cells, including single-crystal wafers, polycrystalline wafers, ribbons, and sheets will continue to dominate the photovoltaic solar cell market for at least the first ten years of the 21st century. The substrate areal throughputs for the leading growth processes are in the range 5-20 m²/h per growth station, and matching process line rates are in place. A near-term goal of 100 m²/h is actively pursued for some of the growth methods. The long-term growth of the crystalline-silicon solar cell industry depends on the development of low-cost polysilicon feedstock (for further expansion of the current growth methods) and on c-Si thin-layer growth or thin films for processes that minimize material consumption and accommodate

monolithic processing. Candidates for such approaches include thin-layer polycrystalline silicon, microcrystalline-silicon thin films, and porous-silicon thin films. For such processes to be viable, they must be capable of matching the throughputs of existing approaches. As the size of the Si PV industry continues to increase, environmental impact of the manufacturing procedures will be a growing concern, and processes that mitigate the impact will be essential.

ACKNOWLEDGMENTS

The authors would like to thank James Gee of the Sandia National Laboratories and Pietro Menna of the National Agency for New Technologies Energy & Environment, Portici, Italy, for helpful discussions. This work is supported by the U.S. DOE under Contract number DE-AC36-98-GO10337.

REFERENCES

-
- 1 P.D. Maycock, editor, *PV News*, February 1999.
 - 2 Y.S. Tsuo, J.M. Gee, P. Menna, D.S. Strebkov, A. Pinov, and V. Zadde, "Environmentally Benign Silicon Solar Cell Manufacturing," Proc. 2nd World Conf. on PV Solar Energy Conversion, 1199 (1998).
 - 3 Y.S. Tsuo, P. Menna, T.H. Wang, and T.F. Cizek, "New Opportunities in Crystalline Silicon R&D," American Institute of Physics Conf. Proc., **462**, 453 (1998).
 - 4 M.G. Mauk, P.E. Sims, and R.B. Hall, "Feedstock for Crystalline Silicon Solar Cells," American Institute of Physics Conf. Proc., **404**, 21 (1997).
 - 5 K.M. Mitchell, "The Status of Polysilicon Feedstock," American Institute of Physics Conf. Proc., **462**, 362 (1998).
 - 6 Summary of the Panel Discussions of the Sixth Workshop on the Role of Impurities and Defects in Silicon Device Processing, NREL/SP-413-21640, September 1996.
 - 7 L.C. Rogers, *Handbook of Semiconductor Silicon Technology*, W.C. O'Mara, R.B. Herring, and L.P. Hunt, editors, Noyes Publications, New Jersey, USA (1990).
 - 8 P. Frankl, H. Lee, and N. Wolfgang, *Industrial Ecology*, R.U. Ayres and L.W. Ayres, editors, Edward Elgar Publishing Co., Cheltenham, UK (1996).
 - 9 P. Menna, Y.S. Tsuo, M.M. Al-Jassim, S.E. Asher, R. Matson, and T.F. Cizek, "Purification of Metallurgical-Grade Silicon by Porous-Silicon Etching," Proc. 2nd World Conf. on PV Solar Energy Conversion, 1232 (1998).
 - 10 N. Nakamura, M. Abe, K. Hanazawa, H. Baba, N. Yuge, and Y. Kato, "Development of NEDO Melt-Purification Process for Solar Grade Silicon and Wafers," Proc. 2nd World Conf. on PV Solar Energy Conversion, 1193 (1998).
 - 11 T.H. Wang, T.F. Cizek, C.R. Schwerdtfeger, H. Moutinho, and R. Matson, "Growth of Silicon Thin Layers on Cast MG-Si from Metal Solutions for Solar Cells," *Solar Energy Materials and Solar Cells*, **41/42**, 19 (1996).
 - 12 T.H. Wang and T.F. Cizek, "Impurity Segregation in LPE Growth of Silicon from Cu-Al Solutions," *J. Crystal Growth*, **174**, 176 (1997).

-
- 13 F.R. Faller, V. Henninger, A. Hurrle, and N. Schillinger, "Optimization of the CVD Process for Low-Cost Crystalline-Silicon Thin-Film Solar Cells," Proc. 2nd World Conf. on PV Solar Energy Conversion, 1278 (1998).
 - 14 K. Yamamoto, M. Yoshimi, T. Suzuki, Y. Tawada, Y. Okamoto, and A. Nakajima, "Below 5-um Thin Film Poly-Si Solar Cell on Glass Substrate Fabricated at Low Temperature," Proc. 2nd World Conf. on PV Solar Energy Conversion, 1284 (1998).
 - 15 A. Lambertz, B.S. Richards, A.B. Sproul, T. Puzzer, and M. Gross, "Sputter Deposited and Solid Phase Crystallized Silicon Films for Solar Cells, " Proc. 2nd World Conf. on PV Solar Energy Conversion, 1507 (1998).
 - 16 K. Yamamoto, M. Yoshimi, T. Suzuki, Y. Tawada, Y. Okamoto, A. Nakajima, and S. Igari, "Below 5 um Thin Film Poly-Si Solar Cell on Glass Substrate Fabricated at Low Temperature," Proc. 2nd World Conf. on PV Solar Energy Conversion, 1284 (1998).
 - 17 A. Slaoui, R. Monna, D. Angermeier, S. Bourdais, and J.C. Muller, "Polycrystalline Silicon Films Formation on Foreign Substrates by a Rapid Thermal-CVD Technique", Proc. 26th IEEE PV Specialists Conf., 627 (1997).
 - 18 W. Luft and Y.S. Tsuo, "Microcrystalline Silicon and Silicon Carbide," Chapter 15, *Hydrogenated Amorphous Silicon Alloy Deposition Processes*, Marcel Dekker, Inc., New York (1993).
 - 19 E. Edelberg, S. Bergh, R. Naone, M. Hall, and E.S. Aydil, "Luminescence from Plasma Deposited Silicon Films," J. Appl. Phys., **81**, 2410 (1997).
 - 20 J. Meier, P. Torres, R. Platz, S. Dubail, U. Kroll, J.A. Anna Selvan, N. Pellaton Vaucher, Ch. Hof, D. Fischer, H. Keppner, A. Shah, K.-D. Ufert, P. Giannoules, and J. Koehler, "On the Way Towards High Efficiency Thin Film Silicon Solar Cells by the Micromorph Concept," Materials Research Society Symposium Proceedings, **420**, 3 (1996).
 - 21 J. Meier, H. Keppner, S. Dubail, Y. Ziegler, L. Feitknecht, P. Torres, Ch. Hof, U. Kroll, D. Fischer, J. Cuperus, J.A. Anna Selvan, and A. Shah, "Microcrystalline and Micromorph Thin-Film Silicon Solar Cells," Proc. 2nd World Conf. on PV Solar Energy Conversion, 375 (1998).
 - 22 L.T. Canham, "Silicon Quantum Wire Array Fabrication by Electrochemical and Chemical Dissolution of Wafers," Appl. Phys. Lett., **57**, 1046 (1990).
 - 23 Y.S. Tsuo, Y. Xiao, and C.A. Moore, "Device Applications of Porous and Nanostructured Silicon," in *Porous Silicon*, Z.C. Feng and R. Tsu, editors, 347, World Scientific Publishing Co., Singapore, (1994).
 - 24 P. Menna and Y.S. Tsuo, "Solar Cells Using Porous Silicon," in *Properties of Porous Silicon*, L. Canham, editor, 384, INSPEC, The Institute of Electrical Engineers, London, (1997).
 - 25 J. Zettner, H.V. Campe, M. Thoenissen, R. Auer, J. Ackermann, Th. Hierl, R. Brendel, and M. Schulz, "Porous Silicon Reflector for Thin Silicon Solar Cells, " 2nd World Conf. on PV Solar Energy Conversion, 1766 (1998).
 - 26 L. Kore and G. Bosman, "Feasibility of Porous Silicon as a Primary Material in Solar Cells," Solar Energy Materials and Solar Cells, **57**, 31 (1999).
 - 27 K.A. Munzer, K.T. Holdermann, R.E. Schlosser, and S. Sterk, "Improvement and Benefits of Thin Crystalline Silicon Solar Cells," Proc. 2nd World Conf. on PV Solar Energy Conversion, 1214 (1998).
 - 28 W. Wettling, "High Efficiency Silicon Solar Cells: State of the Art and Trends," Solar Energy Materials and Solar Cells, **38**, 487 (1995).

-
- 29 R. Gonsiorawski, ASE Americas, Inc., "Thermal Bond Aging of Thick Film Silver Metallized Solar Cells," Presented at the Workshop on Solder-Joint Durability, organized by Sandia National Laboratories, Feb. 1999.
- 30 P.J. Timans, "Rapid Thermal Processing Technology for the 21st Century," *Materials Science in Semiconductor Processing*, **1**, 169 (1998).
- 31 W. DeHart and K. Johnsgard, "New Development in Rapid Thermal Processing," *Solid State Technology*, February, 107, (1996).
- 32 D. Mathiot, A. Lachiq, A. Slaoui, S. Noel, J.C. Miller, and C. Dubois, "Phosphorus Diffusion from a Spin-on Doped Glass (SOD) Source During Rapid Thermal Annealing," *Materials Science in Semiconductor Processing*, **1**, 231 (1998).
- 33 U. Besi-Vetrella, E. Salza, L. Pirozzi, S. Noel, A. Slaoui, and J.C. Muller, "Selective Doping of Silicon by Rapid Thermal and Laser Assisted Processes," *Materials Science in Semiconductor Processing*, **1**, 325 (1998).
- 34 Y.S. Tsuo, J.R. Pitts, M.D. Landry, P. Menna, C.E. Bingham, A. Lewandowski, and T.F. Ciszek, "High-Flux Solar Furnace Processing of Silicon Solar Cells," *Solar Energy Materials and Solar Cells*, **41/42**, 41 (1996).
- 35 R. Singh, V. Parihar, S. Venkataraman, K.F. Poole, R.P.S. Thakur, and A. Rohatgi, "Changing from Rapid Thermal Processing to Rapid Photothermal Processing: What Does it Buy for a Particular Technology?" *Materials Science in Semiconductor Processing*, **1**, 219 (1998).
- 36 Y.S. Tsuo, P. Menna, J.R. Pitts, K.R. Jantzen, S.E. Asher, M.M. Al-Jassim, and T.F. Ciszek, "Porous Silicon Gettering," *Proc. 25th IEEE Photovoltaic Specialists Conf.*, 461 (1996).

REPORT DOCUMENTATION PAGE			Form Approved OMB NO. 0704-0188
Public reporting burden for this collection of information is estimated to average 1 hour per response, including the time for reviewing instructions, searching existing data sources, gathering and maintaining the data needed, and completing and reviewing the collection of information. Send comments regarding this burden estimate or any other aspect of this collection of information, including suggestions for reducing this burden, to Washington Headquarters Services, Directorate for Information Operations and Reports, 1215 Jefferson Davis Highway, Suite 1204, Arlington, VA 22202-4302, and to the Office of Management and Budget, Paperwork Reduction Project (0704-0188), Washington, DC 20503.			
1. AGENCY USE ONLY (Leave blank)	2. REPORT DATE May 1999	3. REPORT TYPE AND DATES COVERED Conference Paper	
4. TITLE AND SUBTITLE Crystalline-Silicon Solar Cells for the 21 st Century		5. FUNDING NUMBERS C: TA:PV902401	
6. AUTHOR(S) Y.S. Tsuo, T.H. Wang, and T.F. Ciszek		8. PERFORMING ORGANIZATION REPORT NUMBER	
7. PERFORMING ORGANIZATION NAME(S) AND ADDRESS(ES) National Renewable Energy Laboratory 1617 Cole Blvd. Golden, CO 80401-3393		10. SPONSORING/MONITORING AGENCY REPORT NUMBER CP-590-26513	
9. SPONSORING/MONITORING AGENCY NAME(S) AND ADDRESS(ES)		11. SUPPLEMENTARY NOTES	
12a. DISTRIBUTION/AVAILABILITY STATEMENT National Technical Information Service U.S. Department of Commerce 5285 Port Royal Road Springfield, VA 22161		12b. DISTRIBUTION CODE	
13. ABSTRACT (Maximum 200 words) The worldwide market share for crystalline-silicon solar cells has increased steadily in the last 10 years. In 1998, about 87% of the photovoltaic modules shipped worldwide are based on crystalline silicon. This dominance will likely continue into at least the first few years of the 21 st century. The long-term growth of crystalline-silicon solar cells will depend on the development of low-cost polysilicon feedstock, silicon films, and advanced cell and module manufacturing processes.			
14. SUBJECT TERMS photovoltaics, solar cells, silicon, polycrystalline silicon, silicon films, microcrystalline silicon, porous silicon, and polysilicon		15. NUMBER OF PAGES 8	
		16. PRICE CODE	
17. SECURITY CLASSIFICATION OF REPORT Unclassified	18. SECURITY CLASSIFICATION OF THIS PAGE Unclassified	19. SECURITY CLASSIFICATION OF ABSTRACT Unclassified	20. LIMITATION OF ABSTRACT UL